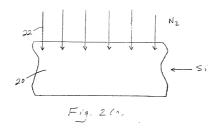
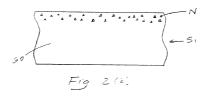
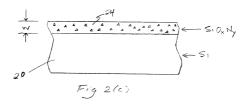
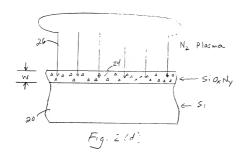


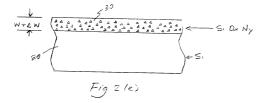
Mukesh Khare et al. FIS920000396US1 1 of 9

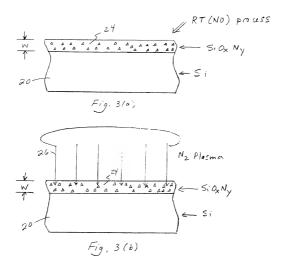


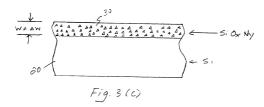












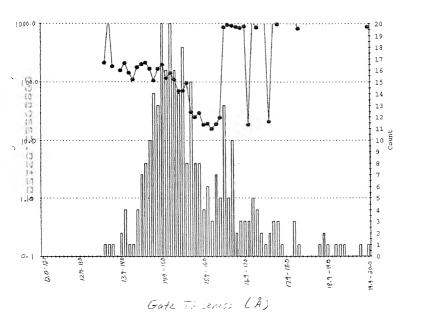
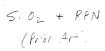
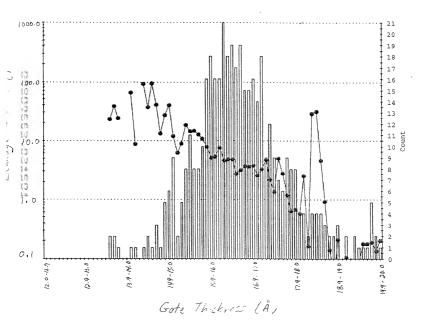


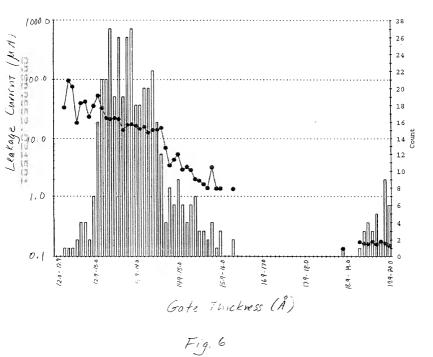
Fig. 4
Fis920000396US1
5 of 9





F19.5

FIS920000396US1 6 of 9



FIS920000396US1 7 of 9

Uniformity of Gate Film

	Mean Thickness (mm)	0
RPN of SiOz (Dry)	1.74	0.287
RPN of SiO2 (Wet)	1.68	0.115
RTNO	1.70	0.0293
RTNO + RPN @ 550°C	1.74	0.0346
RTNO + RPV @ 750°C	1.73	0.0296

Fig. 7

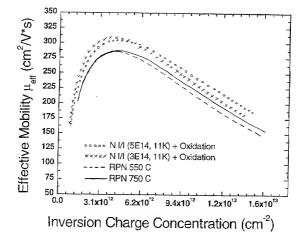


Figure 8